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- (71) **Applicant:** ASML NETHERLANDS B.V. [NL/NL]; P.O. Box 324, 5500 AH Veldhoven (NL).
- (72) **Inventors:** SAFINOWSKI, Pawel; P.O. Box 324, 5500 AH Veldhoven (NL). BROUNS, Derk, Servatius, Gertruda; P.O. Box 324, 5500 AH Veldhoven (NL).
- (74) **Agent:** FILIP, Diana; P.O. Box 324, 5500 AH Veldhoven (NL).

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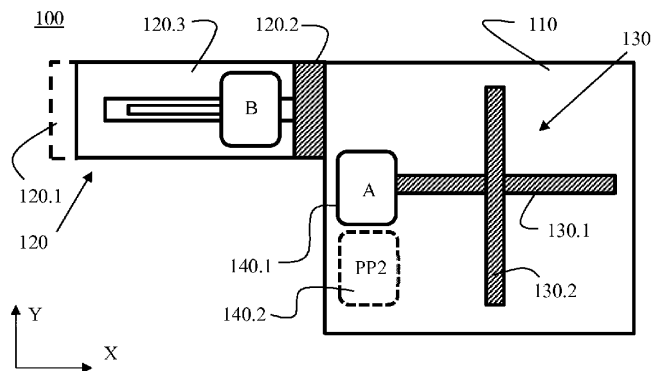


FIG. 2B

- (57) **Abstract:** Inspection apparatus for inspecting an object such as a pellicle for use in an EUV lithographic apparatus, the inspection apparatus comprising: - a vacuum chamber; - a load lock forming an interface between the vacuum chamber and an ambient environment; - a stage apparatus configured to receive the object from the load lock and displace the object inside the vacuum chamber; wherein the vacuum chamber comprises a first parking position and a second parking position for temporarily storing the object.



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